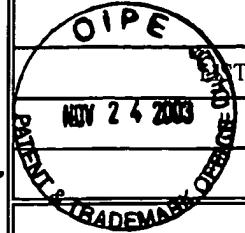
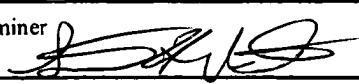


U.S. Department of Commerce, Patent and Trademark Office				Docket No.: AM-6265-P1				
				Serial No.: 10/608,306				
LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary)				Applicant: Tza-Jing GUNG et al.				
				Filing Date: June 26, 2003				
				Group: Unknown 1753				
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
SHV	AA	4,871,433	10/03/89	Wagner et al.	204	192.12		
SHV	AB	5,133,825	07/28/92	Hakamata et al.	156	345		
SHV	AC	5,178,739	01/12/93	Barnes et al.	204	192.12		
SHV	AD	5,482,611	01/09/96	Helmer et al.	204	298.17		
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SHV	AK	6,163,006	12/19/00	Doughty et al.	219	121.43		
FOREIGN PATENT DOCUMENTS (Translation)								
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AR							
	AS							
	AT							
Examiner		Date Considered March 1, 2005						
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LIST OF RELEVANT ART CITED BY APPLICANT <i>NOV 24 2003</i>				Applicant: Tza-Jing GUNG et al.				
(Use several sheets if necessary)				Filing Date: June 26, 2003				
				Group: Unknown 1753				
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
<i>SHV</i>	AA	6,179,973	01/30/01	Lai et al.	204	192.12		
<i>SHV</i>	AB	6,193,854	02/27/01	Lai et al.	204	192.12		
<i>SHV</i>	AC	6,290,825	09/18/01	Fu	204	298.2		
<i>SHV</i>	AD	6,352,629	03/05/02	Wang	204	298.2		
<i>SHV</i>	AE	6,413,383	07/02/02	Chiang et al.	204	192.13	10/10/00	
<i>SHV</i>	AF	6,423,192	07/23/02	Wada et al.	204	192.12	10/27/00	
<i>SHV</i>	AG	US/2003/0089601	05/15/03	Ding et al.	204	298.2	11/14/01	
FOREIGN PATENT DOCUMENTS (Translation)								
		Document Number	Date	Country	Class	Subclass	Yes	No
<i>SHV</i>	AH	0 653 776	5/17/95	Europe	<i>H01J</i>	<i>37/34</i>	X	
<i>SHV</i>	AI	EP 1 091 016	4/11/01	Europe	<i>C23C</i>	<i>14/35</i>	X	
<i>SHV</i>	AJ	EP 1 119 017	7/25/01	Europe	<i>H01J</i>	<i>37/34</i>	X	
<i>SHV</i>	AK	EP 1 174 902	01/23/02	Europe	<i>H01J</i>	<i>37/34</i>	X	
<i>SHV</i>	AL	WO 00/05745	02/03/00	PCT	<i>H01J</i>	<i>37/34</i>	X	
<i>SHV</i>	AM	WO 02/11176	02/07/02	PCT	<i>H01J</i>	<i>37/34</i>	X	
<i>SHV</i>	AN	WO 02/37528	05/10/02	PCT	<i>H01J</i>	<i>37/34</i>	X	
<i>SHV</i>	AO	10204614	08/04/98	Japan	<i>C23C</i>	<i>14/00</i>	Abstract	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
<i>SHV</i>	AR	Ashtiani et al., "A new hollow-cathode magnetron source for 0.10μm copper applications", 0-7803-6327-2, 2000, pp. 37-39						
	AS							
	AT							
Examiner: <i>SHV</i>	Date Considered:	<i>March 1, 2003</i>						
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